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PATENT APPLICATION
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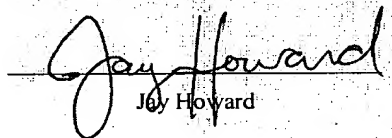


IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: Ajit P. Paranjpe et al.
Serial No.: 09/864,714
Filing Date: May 23, 2001
Group Art Unit: 2814
Examiner: Rao, Shrinivas H.
Title: *Atomic Layer Deposition For Fabricating Thin Films*

MAIL STOP - AMENDMENT
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

I hereby certify that this correspondence is being deposited with the United States Postal Service as Express Mail No. **EV351293258US** in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313, on July 23, 2004.


Jay Howard

RESPONSE TO OFFICE ACTION

Dear Sir:

In response to the Office Action mailed April 23, 2004 (Paper No. 10), Applicants respectfully request that the Examiner reconsider the application in view of the following amendments and remarks:

Amendments to Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 7 of this paper.